QUARTZ **PCI-AM** Version 2.0
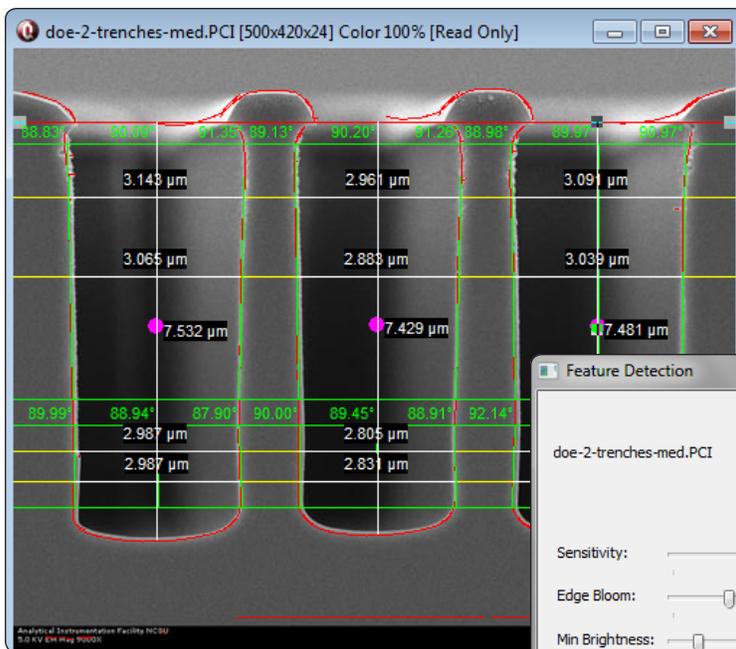
Automated Measurement for Semiconductor Features

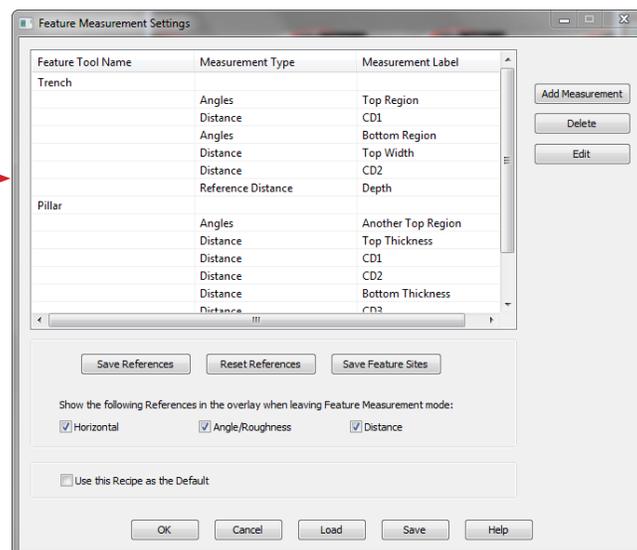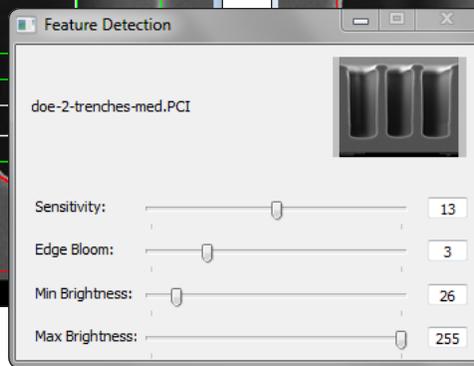QUARTZ IMAGING CORPORATION

Version 2.0

- **More Advanced Edge Detection Technique**
  - **Works with more types of images**
  - **Works with more types of features**
- **More Feature Measurements**
- **More User Settings**

Trench Measurements
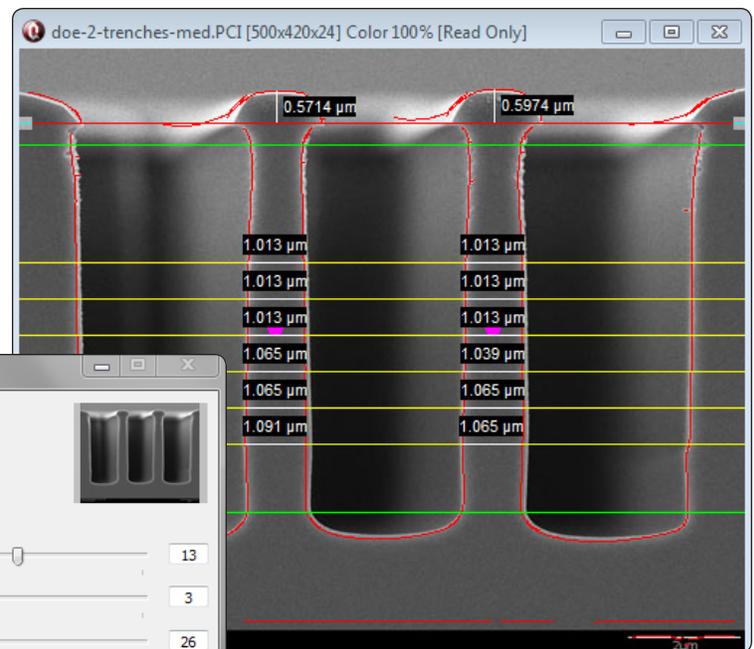

Pillar Measurements

Create Recipes for Measurement Types, Locations and Labels

New Edge Detection Technique with Sensitivity, Edge Bloom and Brightness Control

QUARTZ PCI-AM

PCI-AM FEATURES

- **2 Levels of Automation**
  - Single Image
  - Multiple Images

- **Single Click Measurement of:**
  - Trenches/Pillars
    - Sidewall & Center Angles
    - Line Edge Roughness
    - By Regions of Trench/Pillar

- **Multiple Images Measured with Single Click**
  - Save Measurement Settings from one image
  - Single Click executes all measurements for similar images

JUST CLICK **AND THAT'S IT!**

955 nm
932 nm
920 nm
841 nm
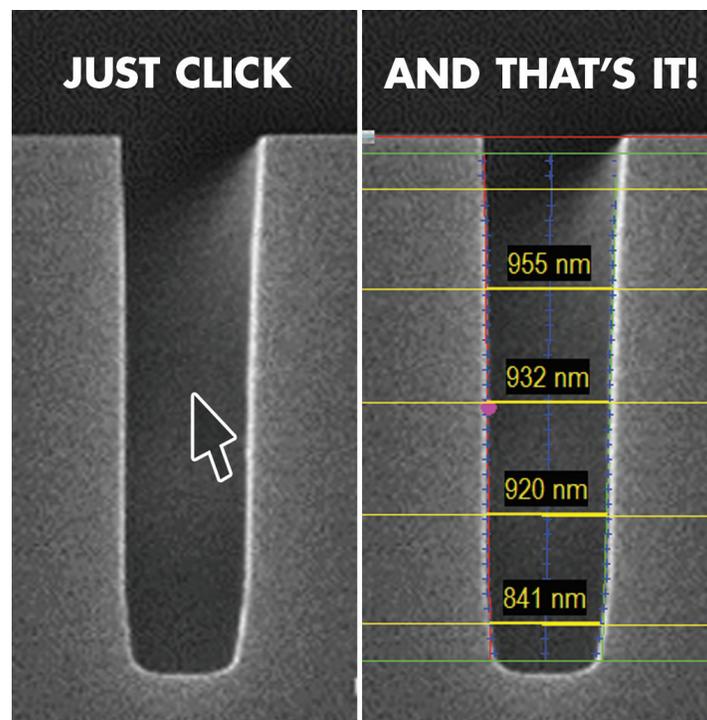
PCI-AM ADVANTAGES

With PCI-AM you will:

- **Save Time**

- **Increase Measurement Accuracy**

- **Increase Measurement Consistency**

- **Export Data Easily into CSV File**

- **Generate Reports Easily with Images and Data**

PLANNED for VERSION 2.5

- **Top View Hole Measurements**
  - Roundness
  - Area
- **Pre-defined CD Measurement Locations**